Supporting Information

High Performance Polarization-sensitive Self-Powered Imaging photodetectors based on p-Te/n-MoSe₂ van der Waals Heterojunction with strong interlayer transition

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Fig. S1 Growth mechanism of solution-grown Te nanosheets. (a-c) Optical image of morphology evolution from the nanowire (a) through intermediate state (b) to the nanosheets (c) of Te grown by solution-grown.



Fig. S2 EDS elemental mapping for Te nanosheet. Inset: low- magnification TEM image of Te nanosheet.



Fig. S3 Nanostructure for 2D Te nanosheet. (a-b) Crystal structure of Te nanosheet viewed from the b-axis (a) and viewed from the c-axis (b).



Fig. S4 Material characterization of MoSe₂ nanosheet. (a) Low-magnification TEM image of MoSe₂ nanosheet. (b) HR-TEM image taken from the MoSe₂ nanosheet. (c) Diffraction pattern of MoSe₂ nanosheet.



Fig. S5 AFM image of p-Te/n-MoSe₂ heterojunction device.



Fig. S6 Raman intensity mapping collected at A_1 (Te: 119 cm⁻¹) and A_{1g} (MoSe₂: 238 cm⁻¹).



Fig. S7 Top view (a) and side view (b) crystal structure of p-Te/n-MoSe₂ heterojunction.



Fig. S8 Time-resolved photovoltaic response of the heterostructure under different laser powers intensity of 405 nm at V = 0 V.



Fig. S9 Electrical power under varied power intensities (405 nm).



Fig. S10 Band alignment of p-Te/n-MoSe₂ heterostructure before contact.



Fig. S11 Extracted I_{sc} and V_{oc} under different laser powers intensity of 405 nm.



Fig. S12 Time-dependent photoresponse of the p-Te/n-MoSe₂ photodetector at zero bias voltage after 8 weeks storage.



Fig. S13 (a) Optical image of the fabricated MoSe₂ FET device. (b) Polarized Raman intensity mapping of MoSe₂ nanosheet as a function of wave number and incident angle. (c) Polar plot of A_{1g} mode intensity in cross-polarized configurations. (d) Polar plot of E^{1}_{2g} mode intensity in cross-polarized configurations. (e) Polar diagram of the polarized photocurrent for the incident wavelengths of 405 nm (0.3 mW/cm²) at 1 V. (f) Polar plots of the angle-dependent mobility as a function of the polarization angle.



Fig. S14 Polarization-sensitive photodetection of p-Te/n-MoSe₂ heterostructure. (a) Polarized photocurrent under 0 V for the incident wavelengths 635 nm (5.968 mW/cm²). (b) Polar diagram of the polarized photocurrent for the incident wavelengths of 635 nm at zero bias voltage, and the anisotropic ratio are 13.97.



Fig. S15 The anisotropic ratio of another three constructed p-Te/n-MoSe₂ heterojunction device.

Table S1 Comparison of the device performances with previously reported 2D material-based photodetectors.

Material	Wavelength (nm)	voltage (V)	Responsivity (<i>R</i>) (mAW ⁻¹)	Detectivity (D*) (Jones)	On/off ratio	Anisotropic ratio	Ref
Te/MoSe ₂	405	0	2106	$\approx 10^{13}$	~10 ⁵	15.87	This work
Те	1550	1	4.56 x 10 ²	-	-	2.39	1
Те	400-1700	5	1.6 x 10 ⁴	2.9 x 10 ⁹	3 x 10 ³	0.95	2
MoS ₂	400-520	2	3500	2 x 10 ¹¹	-	2	3
Black phosphor us	1550	0.15	14.2	-	-	8.7	4
1T'- MoTe ₂ /T _d -MoTe ₂	532-1060	0	0.4	1.07 x 10 ⁸	-	2.72	5
GeSe/Mo S ₂	380-1064	0	105	1.46 x 10 ¹⁰	$\begin{array}{ccc} 3.6 & x \\ 10^4 & \end{array}$	2.95	6
MoS ₂ /Ga As	780	0	35.2	1.96 x 10 ¹³		4.8	7

References

- 1 L. Tong, X. Huang, P. Wang, L. Ye, M. Peng, L. An, Q. Sun, Y. Zhang, G. Yang, Z. Li, F. Zhong, F. Wang, Y. Wang, M. Motlag, W. Wu, G. J. Cheng, W. Hu, Nat. Commun. 2020, **11**, 2308.
- 2 M. Amani, C. Tan, G. Zhang, C. Zhao, J. Bullock, X. Song, H. Kim, V. R. Shrestha, Y. Gao, K. B. Crozier, M. Scott, A. Javey, ACS Nano 2018, 12, 7253.
- 3 L. Tong, X. Duan, L. Song, T. Liu, L. Ye, X. Huang, P. Wang, Y. Sun, X. He, L. Zhang, K. Xu, W. Hu, J. Xu, J. Zang, G. J. Cheng, Applied Materials Today 2019, **15**, 203.
- 4 P. K. Venuthurumilli, P. D. Ye, X. Xu, ACS Nano 2018, 12, 4861.
- 5 J. Lai, X. Liu, J. Ma, Q. Wang, K. Zhang, X. Ren, Y. Liu, Q. Gu, X. Zhuo, W. Lu, Y. Wu, Y. Li, J. Feng, S. Zhou, J. Chen, D. Sun, Adv. Mater. 2018, **30**, 1707152.
- 6 Y. Xin, X. Wang, Z. Chen, D. Weller, Y. Wang, L. Shi, X. Ma, C. Ding, W. Li, S. Guo, R. Liu, ACS Appl. Mater. Inter. 2020, **12**, 15406.
- 7 C. Jia, D. Wu, E. Wu, J. Guo, Z. Zhao, Z. Shi, T. Xu, X. Huang, Y. Tian, X. Li, J. Mater. Chem. C. 2019, 7, 3817.